

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (Currently Amended) An ink jet printhead comprising:
a plurality of nozzles;
a bubble forming chamber corresponding to each of the nozzles respectively;
at least one heater element disposed in each of the bubble forming chambers
respectively, ~~the each~~ heater element being in the form of a cantilever beam having a
~~supported end and a free end~~ configured for thermal contact with a bubble forming liquid;
~~such that, liquid, such that:~~
heating the heater element to a temperature above the boiling point of the
bubble forming liquid forms a gas bubble that causes the ejection of a drop of an
ejectable liquid through the nozzle corresponding to that heater element; wherein,
the heater element has at least one bubble nucleation section, each bubble
nucleation section having a smaller cross section than the remainder of the heater
element; and
a projecting nozzle rim formed about each of the nozzles respectively, each nozzle
rim being configured to direct the drops ejected from the respective nozzle in a particular
direction.
2. (Cancelled)
3. (Original) The printhead of claim 1 wherein the bubble forming chamber has a
circular cross section and the heater element has arcuate sections that are concentric with the
circular cross section.
4. (Cancelled)
5. (Original) The printhead of claim 1 wherein the bubble forming liquid and the
ejectable liquid are of a common body of liquid.
6. (Original) The printhead of claim 1 being configured to print on a page and to be a
page-width printhead.

7. (Cancelled)

8. (Original) The printhead of claim 1 wherein each heater element is configured such that an actuation energy of less than 500 nanojoules (nJ) is required to be applied to that heater element to heat that heater element sufficiently to form a said bubble in the bubble forming liquid thereby to cause the ejection of a said drop.

9. (Cancelled)

10. (Original) The printhead of claim 1 comprising a substrate having a substrate surface, wherein the areal density of the nozzles relative to the substrate surface exceeds 10,000 nozzles per square cm of substrate surface.

11. (Original) The printhead of claim 1 wherein each heater element has two opposite sides and is configured such that a said gas bubble formed by that heater element is formed at both of said sides of that heater element.

12. (Previously Presented) The printhead of claim 1 wherein the bubble which each heater element is configured to form is collapsible and has a point of collapse, and wherein each heater element is configured such that the point of collapse of a bubble formed thereby is spaced from that heater element.

13. (Original) The printhead of claim 1 comprising a structure that is formed by chemical vapor deposition (CVD), the nozzles being incorporated on the structure.

14. (Original) The printhead of claim 1 comprising a structure which is less than 10 microns thick, the nozzles being incorporated on the structure.

15. (Previously Presented) The printhead of claim 1 comprising a plurality of the bubble forming chambers each corresponding to a respective nozzle, and a plurality of said heater elements being disposed within each chamber, the heater elements within each chamber being formed on different respective layers to one another.

16. (Original) The printhead of claim 1 wherein each heater element is formed of solid material more than 90% of which, by atomic proportion, is constituted by at least one periodic element having an atomic number below 50.

17. (Original) The printhead of claim 1 wherein each heater element includes solid material and is configured for a mass of less than 10 nanograms of the solid material of that heater element to be heated to a temperature above said boiling point thereby to heat said part of the bubble forming liquid to a temperature above said boiling point to cause the ejection of a said drop.

18. (Previously Presented) The printhead of claim 1 wherein each heater element is covered by a conformal protective coating, the coating of each heater element having been applied substantially to all sides of the heater element simultaneously such that the coating is seamless.

19. (Currently Amended) A printer system which incorporates a printhead, the printhead comprising:

a plurality of nozzles;
a bubble forming chamber corresponding to each of the nozzles respectively;
at least one heater element disposed in each of the bubble forming chambers respectively, ~~the each heater element being in the form of a cantilever beam having a supported end and a free end configured for thermal contact with a bubble forming liquid; such that, liquid, such that:~~

heating the heater element to a temperature above the boiling point of the bubble forming liquid forms a gas bubble that causes the ejection of a drop of an ejectable liquid through the nozzle corresponding to that heater element; wherein,

the heater element has at least one bubble nucleation section, each bubble nucleation section having a smaller cross section than the remainder of the heater element; and

a projecting nozzle rim formed about each of the nozzles respectively, each nozzle rim being configured to direct the drops ejected from the respective nozzle in a particular direction.

20. (Cancelled)

21. (Original) The system of claim 19 wherein the bubble forming chamber has a circular cross section and the heater element has arcuate sections that are concentric with the circular cross section.

22. – 23. (Cancelled)

24. (Original) The system of claim 19 wherein the bubble forming liquid and the ejectable liquid are of a common body of liquid.

25. (Original) The system of claim 19 being configured to print on a page and to be a page-width printhead.

26. (Cancelled)

27. (Original) The system of claim 19 wherein each heater element is configured such that an actuation energy of less than 500 nanojoules (nJ) is required to be applied to that heater element to heat that heater element sufficiently to form a said bubble in the bubble forming liquid thereby to cause the ejection of a said drop.

28. (Cancelled)

29. (Original) The system of claim 19 comprising a substrate having a substrate surface, wherein the areal density of the nozzles relative to the substrate surface exceeds 10,000 nozzles per square cm of substrate surface.

30. (Original) The system of claim 19 wherein each heater element has two opposite sides and is configured such that a said gas bubble formed by that heater element is formed at both of said sides of that heater element.

31. (Previously Presented) The system of claim 19 wherein the bubble which each heater element is configured to form is collapsible and has a point of collapse, and wherein each heater element is configured such that the point of collapse of a bubble formed thereby is spaced from that heater element.

32. (Original) The system of claim 19 comprising a structure that is formed by chemical vapor deposition (CVD), the nozzles being incorporated on the structure.

33. (Original) The system of claim 19 comprising a structure which is less than 10 microns thick, the nozzles being incorporated on the structure.

34. (Previously Presented) The system of claim 19 comprising a plurality of the bubble forming chambers each corresponding to a respective nozzle, and a plurality of said heater elements being disposed within each chamber, the heater elements within each chamber being formed on different respective layers to one another.

35. (Original) The system of claim 19 wherein each heater element is formed of solid material more than 90% of which, by atomic proportion, is constituted by at least one periodic element having an atomic number below 50.

36. (Original) The system of claim 19 wherein each heater element includes solid material and is configured for a mass of less than 10 nanograms of the solid material of that heater element to be heated to a temperature above said boiling point thereby to heat said part of the bubble forming liquid to a temperature above said boiling point to cause the ejection of a said drop.

37. (Previously Presented) The system of claim 19 wherein each heater element is covered by a conformal protective coating, the coating of each heater element having been applied substantially to all sides of the heater element simultaneously such that the coating is seamless.

38. (Currently Amended) A method of ejecting drops of an ejectable liquid from a printhead, the printhead comprising:

- a plurality of nozzles;
- a bubble forming chamber corresponding to each of the nozzles respectively;
- at least one heater element disposed in each of the bubble forming chambers respectively, the heater element being in the form of a cantilever beam having a supported

end and a free end configured for thermal contact with a bubble forming ~~liquid~~liquid, wherein,

the heater element has at least one bubble nucleation section, each bubble nucleation section having a smaller cross section than the remainder of the heater element; and

a projecting nozzle rim formed about each of the nozzles respectively, each nozzle rim being configured to direct the drops ejected from the respective nozzle in a particular direction, the method comprising the steps of:

heating the heater element to a temperature above the boiling point of the bubble forming liquid to form a gas bubble that causes the ejection of a drop of an ejectable liquid from the nozzle; and

supplying the nozzle with a replacement volume of the ejectable liquid equivalent to the ejected drop.

39. (Cancelled)

40. (Original) The method of claim 38 wherein the bubble forming chamber has a circular cross section and the heater element has arcuate sections that are concentric with the circular cross section.

41. (Cancelled)

42. (Original) The method of claim 38 wherein the bubble forming liquid and the ejectable liquid are of a common body of liquid.

43. (Original) The method of claim 38 wherein the printhead is configured to print on a page and to be a page-width printhead.

44. (Original) The method of claim 38 wherein said step of heating the at least one heater element is effected by applying an actuation energy of less than 500nJ to each such heater element.

45. (Cancelled)

46. (Original) The method of claim 38 wherein the printhead includes a substrate on which said nozzles are disposed, the substrate having a substrate surface and the areal density of the nozzles relative to the substrate surface exceeding 10,000 nozzles per square cm of substrate surface.

47. (Original) The method of claim 38 wherein the at least one heater element has two opposing sides and the bubble is generated at both of said sides of each heated heater element

48. (Original) The method of claim 38 wherein the generated bubble is collapsible and has a point of collapse, and is generated such that the point of collapse is spaced from the at least one heater element.

49. (Original) The method of claim 38 wherein the printhead has a structure that is less than 10 microns thick and which incorporates said nozzles thereon.

50. (Original) The method of claim 38 wherein the nozzles of the printhead are formed by chemical vapor deposition (CVD).

51. (Previously Presented) The method of claim 38 wherein the printhead has a plurality of the bubble forming chambers each chamber corresponding to a respective nozzle and a plurality of said heater elements are formed in each of the chambers, such that the heater elements in each chamber are formed on different respective layers to one another.

52. (Original) The method of claim 38 wherein the heater elements are formed of solid material more than 90% of which, by atomic proportion, is constituted by at least one periodic element having an atomic number below 50.

53. (Original) The method of claim 38 wherein the heater elements include solid material and wherein the step of heating at least one heater element comprises heating a mass of less than 10 nanograms of the solid material of each such heater element to a temperature above said boiling point.

54. (Previously Presented) The method of claim 38 wherein a conformal protective coating is applied to all sides of each of the heater elements simultaneously, such that the coating is seamless.